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Simulation and test of 3D detectors in Glasgow

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Outline



- Single-type column 3D detectors
 - Fabricated by ITC-irst (Trento) and CNM (Barcelona)
 - Results from simulation and test
- Double-sided 3D detectors
 - Designed by CNM
 - Results from simulation
- Conclusions

Single-type column 3D detectors



- n+ columns on p- substrate, p+ implant on backside
 - 10x10 columns arrays
 - Column depth 150 μm
 - Diameter 10 μm
 - Pitch 80 μ m (100 μ m for detector 4)
- FZ silicon, 500 μ m, ρ >5 k Ω .cm (doping conc. 2.8*10¹² cm⁻³)





Depletion behaviour without p-stop



0V Depletion of a singlecolumn 3D detector with SpaceCharge 0 -3E+11 2.5V oxide charge present -6E+11 -9E+11 -1.2E+12 -1.5E+12 -1.8E+12 No p-stop -2.1E+12 -2.4E+12 -2.7E+12 -3E+12 × × 5V 7.5V 10V pitch/2

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C-V measurements: without p-stop

-P-stop between guard ring and active area

-No single-hole p-stop

3d2 and 3d4

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- 10 kHz
- **Full depletion** between electrodes at ~ 7 V.
- **Planar-like depletion** afterwards





C-V measurements: with p-stop





CCE (work in progress)

- New CCE setup
 - Strontium-90 2.283MeV β- source
 - Operational, but still needs calibration
 - Results ready for next RD50 meeting

M5 Charge Collection versus Bias voltage









Double-sided 3D detectors





Depletion behaviour





Depletion behaviour





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Electric potential and field



- 1. Overlap region
 - 50 to 250 μm
 - Field pattern like in a standard 3D device
 - Charge carriers swept horizontally towards the electrodes



Electric potential and field



- 1. Overlap region
 - 50 to 250 μm
 - Field pattern like in a standard 3D device
 - Charge carriers swept horizontally towards the electrodes
- 2. Near surface
 - Reduced field strength
 - Increased drift distance
 - Longer collection times

Detail of electric field (V/cm) around top of double-sided 3D device (100V bias)



Electric potential and field



140000

- 1. Overlap region
 - 50 to 250 μm
 - Field pattern like in a standard 3D device
 - Charge carriers swept horizontally towards the electrodes
- 48 280000 (**m**50 **z** 2. Near surface 343000 Reduced field strength Increased drift distance 52 Longer collection times 54 3. Top of the columns High field region 56 - VBD > 215 V The device can be safely operated 30 32 34 36 38 D (um)

44

46

8th RD50 Workshop, 25-28 June 2006

V = 215 V

210000

Charge collection

MIP signal in standard 3D and double-sided 3D (CNM) at 20V





- Comparison with ideal 3D detector
 - Columns all the way through the wafer
 - Same dimensions as double-sided 3D
- V = 20 V
- MIP arriving midway between the electrodes

Ideal 3D:

- All charge collected in 1.5 ns

Double-sided 3D:

- 92% of charge in 3 ns
- 97% in 5 ns



- Charge carriers collected more slowly from the low-field regions near the surfaces
 - This causes the long tail-off
- However, with V = 100 V,
 - 90% of charge collected in 0.75 ns and 99% in 2.8 ns
 - 10-20 ns for a planar detector

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Conclusions



- 3D-single-type columns detectors
 - Simulations and C-V measurements:
 - Depletion behavior depends on p-stop structure
 - Region between electrodes is fully depleted at ~8 V for all devices
 - Depletion continues to backplane much like in a planar device
 - Preliminary CCE results :
 - 100% of the charge collected at 30 V for a 300 μ m thick detector
 - Charge collected even at 0 V due to already depleted regions
- Double-sided 3D detectors:
 - Very promising characteristics from simulations:
 - Device fully depleted at 10 V
 - Breakdown voltage > 200 V
 - Where columns overlap the behaviour is similar to that of an ideal 3D
 - There are low field regions but still rapid charge collection



Extra slides

Experimental setup



- Glasgow has just installed a new Cascade Microtech probe station
 - Allows temperature and humidity control, electrostatic shielding, more reliable calibration etc.
 - Up to 12" wafers
- Keithley 4200-SCS Semiconductor Characterization System
- HP 4284A LCRMeter
 - Measurements up to 40 V



Simulated devices



Simulations were produced using ISE-TCAD 7.0

- Dimensions match devices produced by ITC-irst
- Bulk doping concentration was obtained from the quoted minimum resistivity of the Float Zone silicon used by IRST



C-V measurements



- Guard ring not biased, 10 kHz
- For V > 10 V the C-V curve is similar to that of a planar device.
- P-stop modifies depletion behaviour



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